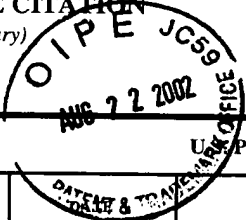


INFORMATION DISCLOSURE CITATION
(Use several sheets if necessary)



Docket Number (Optional) CIB-1632A(CIB-1635)	Application Number 09/918,395
Applicant(s) RONALD P. READE ET AL.	
Filing Date JULY 30, 2001	Group Art Unit

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
<i>cp</i>		6,312,829	11/2001	Jia et al.	428	450	
<i>cp</i>		6,337,991	01/2002	Li et al.	505	161	

RECEIVED
AUG 28 2002
TC 1700

FOREIGN PATENT DOCUMENTS

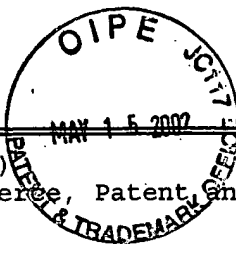
REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

<i>7m</i>	Mao, Y.J. et al.; "STUDY ON THE GROWTH OF BIAXIALLY ALIGNED YTTRIA-STABILIZED ZIRCONIA FILMS DURING ION BEAM ASSISTED DEPOSITION," Journal of Vacuum Science Technology, Vol. A15, No. 5, pp. 2687 thru 2692, September/October 1997.

EXAMINER: <i>Richard McDonald</i>	DATE CONSIDERED: <i>7/30/03</i>
-----------------------------------	---------------------------------

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

FORM PTO-1449 (Modified)
U.S. Department of Commerce, Patent and Trademark OfficeDocket No.
CIB-1632ASerial No.
09/918,395

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use several sheets if necessary)

Applicant
Ronald P. Reade et al.Filing Date
July 30, 2001Group
Unknown

U.S. Patent Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
<i>PM</i>	AA	6,060,375	5/9/00	Owyang et al.	438	585	7/31/96
<i>ym</i>	AB	5,872,080	2/16/99	Arendt et al.	505	238	4/19/95
	AC	5,650,378	7/22/97	Iijima et al.	505	473	8/3/95
	AD	5,432,151	7/11/95	Russo et al.	505	474	7/12/93
	AE	5,262,394	11/16/93	Wu et al.	505	1	12/27/91
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

Foreign Patent Documents

Translation

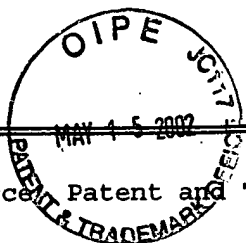
		Document Number	Date	Country	Class	Subclass	Yes	No
	AL	01/08169	07/2000	WIPO				
	AM	01/08170	07/2000	WIPO				
	AN	01/08231	07/2000	WIPO				
	AO	01/08232	07/2000	WIPO				
	AP	01/08235	07/2000	WIPO				

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

AR	Berdahl, P., et al., "Angular Magnetoresistance Provides Texture Information on High- T_c Conductors", <u>Physica C</u> , 195, 1992, pp. 93-102.
AS	Bradley, Mark R., et al., "Theory of Thin-Film Orientation by Ion Bombardment during Deposition", <u>J. Appl. Phys.</u> 60 (12), 15 December 1986, pp. 4160-4164.
AT	Dimos, D., et al., "Superconducting Transport Properties of Grain Boundaries in $\text{YBa}_2\text{Cu}_3\text{O}_x$ Bicrystals", <u>Physical Review B</u> , Vol. 41, No. 7, March 1, 1990, pp. 4038-4049.

Examiner *Goshay M. D...* Date Considered *7/30/03*

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.



FORM PTO-1449 (Modified)
U.S. Department of Commerce Patent and Trademark Office

Docket No. CIB-1632A
Serial No. 09/918,395

INFORMATION DISCLOSURE STATEMENT BY APPLICANT
(Use several sheets if necessary)

Applicant
Ronald P. Reade et al.

Filing Date July 30, 2001
Group Unknown

U.S. Patent Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	BA						
	BB						
	BC						
	BD						
	BE						
	BF						
	BG						
	BH						
	BI						
	BJ						
	BK						

Foreign Patent Documents

							Translation	
		Document Number	Date	Country	Class	Subclass	Yes	No
	BL	01/08236	07/2000	WIPO				
	BM	99/16941	09/1998	WIPO				
	BN	01/08233	07/2000	WIPO				
	BO	01/26165	07/2000	WIPO				
	BP	98/58415	06/1998	WIPO				

RECEIVED
MAY 21 2002
TOLSON

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

BR	Dobrev, D., "Ion-Beam-Induced Texture Formation in Vacuum-Condensed Thin Metal Films", <u>Thin Solid Films</u> 92, 1982, pp. 41-53.
BS	Fork, D.K., et al., "High Critical Currents in Strained Epitaxial $\text{YBa}_2\text{Cu}_3\text{O}_{7-x}$ on Si", <u>Appl. Phys. Lett.</u> 57 (11), 10 September 1990, pp. 1161-1163.
BT	Garrison, S.M., et al., "Observation of Two In-Plane Epitaxial States in $\text{YBa}_2\text{Cu}_3\text{O}_{7-x}$ Films on Yttria-Stabilized ZrO_2 ", <u>Appl. Phys. Lett.</u> 58 (19), 13 May 1991, pp. 2168-2170.

Examiner *Rodney McDonald* Date Considered 7/30/03

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

FORM PTO-1449 (Modified)
U.S. Department of Commerce, Patent and Trademark Office

Docket No.
CIB-1632A

Serial No.
09/918,395

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use several sheets if necessary)

Applicant

Ronald P. Reade et al.

Filing Date
July 30, 2001

Group
Unknown

U.S. Patent Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	CA						
	CB						
	CC						
	CD						
	CE						
	CF						
	CG						
	CH						
	CI						
	CJ						
	CK						

Foreign Patent Documents

Translation

		Document Number	Date	Country	Class	Subclass	Yes	No
	CL	01/15245	07/2000	WIPO				
	CM	01/26164	07/2000	WIPO				
	CN	00/58530	03/2000	WIPO				
	CO	99/17307	09/1998	WIPO				
	CP	01/11428	07/2000	WIPO				

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

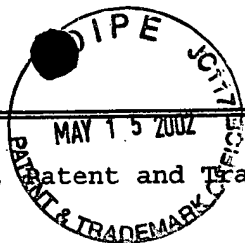
CR	Iijima, Y., et al., "Biaxially Aligned YSZ Buffer Layer on Polycrystalline Substrates", paper prepared for Proceedings of the Fourth International Symposium on Superconductivity, Tokyo, Japan, October 14-17, 1991, pp. 1-4.
CS	Iijima, Y., et al., "In-Plane Aligned YBa ₂ Cu ₃ O _{7-x} Thin Films Deposited on Polycrystalline Metallic Substrates", <u>Appl. Phys. Lett.</u> 60 (6), 10 February 1992, pp. 769-771.
CT	Jia, Q.X., et al., "Sputter Deposition of YBa ₂ Cu ₃ O _{7-x} Films on Si at 500°C with Conducting Metallic Oxide as a Buffer Layer" <u>Appl. Phys. Lett.</u> 57 (3), 16, July 1990, pp. 304-306.

Examiner

Date Considered

7/30/03

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.



FORM PTO-1449 (Modified)
U.S. Department of Commerce, Patent and Trademark Office

Docket No.
CIB-1632A

Serial No.
09/918,395

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use several sheets if necessary)

Applicant

Ronald P. Reade et al.

Filing Date

July 30, 2001

Group

Unknown

U.S. Patent Documents

*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	DA					
	DB					
	DC					
	DD					
	DE					
	DF					
	DG					
	DH					
	DI					
	DJ					
	DK					

Foreign Patent Documents

							Translation	
	Document Number	Date	Country	Class	Subclass	Yes	No	
	DL	00/58044	01/2000	WIPO				
	DM							
	DN							
	DO							
	DP							

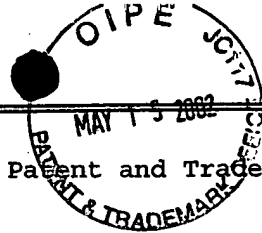
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

DR	Kumar, Ashok, et al., "Synthesis of Superconducting $\text{YBa}_2\text{Cu}_3\text{O}_{7-x}$ Thin Films on Nickel-Based Superalloy Using In Situ Pulsed Laser Deposition, <u>Appl. Phys. Lett.</u> 57 (24), 10 December 1990, pp. 2594-2596.
DS	Lioutas, Ch.B., et al., "Phase Transformation of Hydrogen Free Amorphous Carbon Films under Ion Beam Bombardment", <u>Carbon</u> , Vol. 36, No. 5-6, 1998, pp. 545-548.
DT	Mizutani, T., "Compositional and Structural Modifications of Amorphous SiO_2 by Low-Energy Ion and Neutral Beam Irradiation", <u>Journal of Non-Crystalline Solids</u> 181, 1995, pp. 123-134.

Examiner *Rodney P. Gault* Date Considered

7/30/03

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.



FORM PTO-1449 (Modified)
U.S. Department of Commerce, Patent and Trademark Office

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use several sheets if necessary)

Docket No.

CIB-1632A

Serial No.

09/918,395

Applicant

Ronald P. Reade et al.

Filing Date

July 30, 2001

Group

Unknown

U.S. Patent Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	EA						
	EB						
	EC						
	ED						
	EE						
	EF						
	EG						
	EH						
	EI						
	EJ						
	EK						

Foreign Patent Documents

Translation

		Document Number	Date	Country	Class	Subclass	Yes	No
	EL							
	EM							
	EN							
	EO							
	EP							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

ER	Narumi, E., et al., "Critical Current Density Enhancement in $\text{YBaCu}_3\text{O}_{6.8}$ Films on Buffered Metallic Substrates", <u>Appl. Phys. Lett.</u> 58 (11), 18 March 1991, pp. 1202-1204.
ES	Norton, David P., et al., "High Critical Current Densities in $\text{YBa}_2\text{Cu}_3\text{O}_{7-x}$ Films on Polycrystalline Zirconia", <u>Appl. Phys. Lett.</u> 57 (11), 10 September 1990, pp. 1164-1166.
ET	Pangal, K. et al., "Integration of Amorphous and Polycrystalline Silicon Thin-Film Transistors Through Selective Crystallization of Amorphous Silicon", <u>Appl. Phys. Lett.</u> 75 (14), 4 October 1999, pp. 2091-2093.

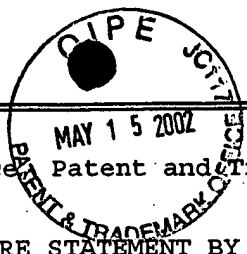
Examiner

Rodney McDonald

Date Considered

7/30/03

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

FORM PTO-1449 (Modified)
U.S. Department of Commerce Patent and Trademark OfficeDocket No.
CIB-1632ASerial No.
09/918,395

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use several sheets if necessary)

Applicant

Ronald P. Reade et al.

July 30, 2001

Group
Unknown

U.S. Patent Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	FA						
	FB						
	FC						
	FD						
	FE						
	FF						
	FG						
	FH						
	FI						
	FJ						
	FK						

Foreign Patent Documents

							Translation	
		Document Number	Date	Country	Class	Subclass	Yes	No
	FL							
	FM							
	FN							
	FO							
	FP							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

FR	Reade, R.P., et al., "Characterization of Y-Ba-Cu-O Thin Films and Yttria-Stabilized Zirconia Intermediate Layers on Metal Alloys Grown by Pulsed Laser Deposition, <u>Appl. Phys. Lett.</u> 59 (6), 5 August 1991, pp. 739-741.
FS	Reade, R.P., et al., "Laser Deposition of Biaxially Textured Yttria-Stabilized Zirconia Buffer Layers on Polycrystalline Metallic Alloys for High Critical Current Y-Ba-Cu-O Thin Films", <u>Appl. Phys. Lett.</u> 61 (18), 2 November 1992, pp. 2231-2233.
FT	Russo, R.E., et al., "Fabrication and Characterization of Y-Ba-Cu-O Thin-Films on Stainless-Steel Substrates", submitted by authors for publication in <u>High Temperature Superconducting Compounds II</u> , edited by S.H. Whang (Minerals, Metals, and Materials Society, Warrendale), 1990, pp. 1-6.

Examiner *Richard J. Smith* Date Considered *7/30/03*

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

FORM PTO-1449 (Modified)
U.S. Department of Commerce, Patent and Trademark Office

Docket No.

CIB-1632A

Serial No.

09/918,395

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use several sheets if necessary)

Applicant

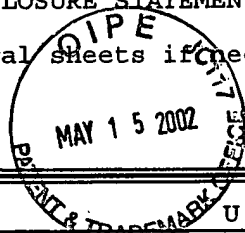
Ronald P. Reade et al.

Filing Date

July 30, 2001

Group

Unknown



U.S. Patent Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

Foreign Patent Documents

Translation

		Document Number	Date	Country	Class	Subclass	Yes	No
	AL							
	AM							
	AN							
	AO							
	AP							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

AR	Russo, R.E., et al., "Metal Buffer Layers and Y-Ba-Cu-O Thin-Films on Pt and Stainless-Steel Using Pulsed Laser Deposition", <u>J. Appl. Phys.</u> 68 (3), 1 August 1990, pp. 1354-1356.
AS	Tiwari, P., et al., "In Situ Single Chamber Laser Processing of YBa ₂ Cu ₃ O _{7-x} Superconducting Thin Films on Si (100) with Yttria-Stabilized Zirconia Buffer Layers", <u>Appl. Phys. Lett.</u> 57 (15), 8 October 1990, pp. 1578-1580.
AT	Van Wyk, G.N., "The Dependence of Ion Bombardment Induced Preferential Orientation on the Direction of the Ion Beam", <u>Radiation Effects Letters</u> , Vol. 57, 1980, pp. 45-50.

Examiner

Date Considered

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

FORM PTO-1449 (Modified)
U.S. Department of Commerce, Patent and Trademark Office

Docket No.
CIB-1632A

Serial No.
09/918,395

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(Use several sheets if necessary)

Applicant

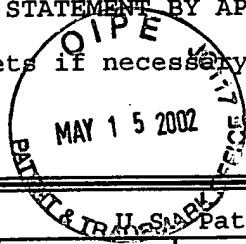
Ronald P. Reade et al.

Filing Date

July 30, 2001

Group

Unknown



Patent Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

Foreign Patent Documents

							Translation	
		Document Number	Date	Country	Class	Subclass	Yes	No
	AL							
	AM							
	AN							
	AO							
	AP							

RECEIVED
MAY 21 2002
TOLSON

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

AR	Van Wyk, G.N., et al., "Ion Bombardment Induced Preferential Orientation in Polycrystalline Cu Targets", <u>Radiation Effects</u> , Vol. 38, 1978, pp. 245-247.
AS	Wang, C.P. et al., "Deposition of In-Plane Textured MgO on Amorphous Si ₃ N ₄ Substrates by Ion-Beam-Assisted Deposition and Comparisons with Ion-Beam-Assisted Deposited Yttria-Stabilized-Zirconia", <u>Appl. Phys. Lett.</u> 71 (20), 17 November 1997, pp. 2955-2957.
AT	Wiesmann, J., et al., "Large-Area Deposition of Biaxially Textured YSZ Buffer Layers Using an IBAD-Process", <u>Nucl. Instr. and Meth. in Phys. Res. B</u> 120, 1996, pp. 290-292.

Examiner

Date Considered

7/30/03

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant